

H 1753

## PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

	In re Application of:	)	·
( to	in to ripproduction of	:	Examiner: Alan D. Diamond
1	TAKAHARU KONDO, ET AL.	)	
iter		:	Group Art Unit: 1753
<b>D</b> D	Application No.: 09/866,665	)	•
10/05		:	
18/05	Filed: May 30, 2001	)	
		:	
	For: SILICON-TYPE THIN FILM	)	
·	FORMATION PROCESS, SILICON	:	
	TYPE THIN FILM, AND	)	
	PHOTOVOLTAIC DEVICE	:	April 6, 2005
	Mail Stop Amendment		
	Commissioner for Patents		
	P.O. Box 1450		
	Alexandria, VA 22313-1450		
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## **AMENDMENT**

Sir:

In response to the Office Action dated January 6, 2005, please amend the above-identified application as follows.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 6, 2005

(Date of Deposit)

When A. Krause (Reg. No. 24,613) (Name of Attorney for Applicants)

April 6, 2005

Signatur

Date of Signature

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